



In place of PTO 1449 Form		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	10/684,120
				Filing Date	October 10, 2003
				Applicant(s)	Christof Baur, et al.
				Art Unit	Unknown
				Examiner Name	Unknown
SHEET	1	OF	1	Attorney Docket Number	34003.55

OTHER PRIOR ART					
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume, issue number(s), publisher, city/country, where published			
JB	AA	C. BAUR, A. BUGACOV, B.E. KOEL, A. MADHUKAR, N. MONTOYA, T.R. RAMACHANDRAN, A.A.R. REQUICHA, R. RESCH and P. WILL; <i>Nanoparticle manipulation by mechanical pushing: underlying phenomena and real-time monitoring</i> ; Nanotechnology 9 (1998) 360-364; August 7, 1998.			
JB	AB	T. NAKAYAMA, D.H. HUANG, M. AONO; <i>Extraction, deposition, and displacement of atoms by STM</i> ; Microelectronic Engineering 32 (1996) 191-201.			
JB	AC	P. MORIARTY, Y.R. MA, M.D. UPWARD, P.H. BETON; <i>Translation, rotation and removal of C60 on Si(100) - 2 x 1 using anisotropic molecular manipulation</i> ; Surface Science 407 (1998) 27-35.			
JB	AD	John M. MICHELSEN, Mark J. DYER, Jim VON EHR; <i>Assembler Construction by Proximal Probe</i> ; Ppaer presented at the 5 th Foresight Conference on Molecular Nanotechnology; Nov. 5-8, 1997, Palo Alto, CA.			
JB	AE	H. TANG, M.T. CUBERES, C. JOACHIM, J.K. GIMZEWSKI; <i>Fundamental considerations in the manipulation of a single C60 molecule on a surface with an STM</i> ; Surface Science 386 (1997) 115-123.			
JB	AF	Jim GIMZEWSKI; <i>Atoms get a big push, or is that a pull?</i> Physics World, November 1997, pp. 27, 28.			
JB	AG	James K. GIMZEWSKI, Christian JOACHIM; <i>Nanoscale Science of Single Molecules Using Local Probes</i> ; Science Molecules Vol. 283; March 12, 1999; pp. 1683-1686.			
JB	AH	D. M. EIGLER, E.K. SCHWEIZER; <i>Positioning single atoms with a scanning tunnelling microscope</i> ; Letters to Nature Vol. 344, April 5, 1990; pp. 524-526.			
JB	AI	Michael R. FALVO, Richard SUPERFINE; <i>Mechanics and friction at the nanometer scale</i> ; Dept. of Physics and Astronomy, The University of North Carolina at Chapel Hill; pp. 1-17.			
JB	AJ	H.J. LEE, W. HO; <i>Single-Bond Formation and Characterization with a Scanning Tunneling Microscope</i> ; Science Reports Vol. 286; November 26, 1999; pp. 1719-1722.			
JB	AK	Seiji HEIKE, Tomihiro HASHIZUME, Yasuo WADA; <i>Nanoneedle formation on silicon (111) surface using a scanning tunneling microscope tip</i> ; J. Appl. Phys. 80 (7); October 1, 1996; pp. 4182-4188.			
JB	AL	D.H. HUANG, Y. YAMAMOTO; <i>Physical mechanism of hydrogen deposition from a scanning tunneling microscopy tip</i> ; Applied Physics A 64 (1997); pp. 419-422.			
JB	AM	J.W. LYDING, T.C. SHEN, J.S. HUBACEK, J.R. TUCKER, G.C. ABELN; <i>Nanoscale patterning and oxidation of H-passivated Si(100) - 2 x 1 surfaces with an ultrahigh vacuum scanning tunneling microscope</i> ; Appl. Phys. Lett. 64 (15); April 11, 1994; pp. 2010-2012.			
JB	AN	Dehuan HUANG, Hironaga UCHIDA; <i>Deposition and subsequent removal of single Si atoms on the Si(111) - 7 x 7 surface by a scanning tunneling microscope</i> ; J. Vac. Sci. Technol. B 12 (4); July/August 1994; pp. 2429-2433.			
JB	AO	D. CHEN, R.K. WORKMAN, D. SARID; <i>Adsorption and decomposition of C60 molecules on Si(111) surfaces</i> ; J. Vac. Sci. Technol. B 14 (2), March/April 1996; pp. 979-981.			
JB	AP	P.H. BETON, A.W. DUNN, P. MORIARTY; <i>Manipulation of C60 molecules on a Si surface</i> ; Appl. Phys. Lett. 67 (8); pp. 1075-1077; August 21, 1995			
JB	AQ	H. TAKASHIMA, M. NAKAYA, A. YAMAMOTO, A. HASHIMOTO; <i>Two-step growth of C60 films on H-terminated Si(111) substrate</i> ; Journal of Crystal Growth 227-228 (2001), pp. 825-828			
JB	AR	F. OWMAN, P. MARTENSSON; <i>STM study of structural defects on in situ prepared Si(111) X 1-H surfaces</i> ; Surface Science 324 (1995), pp. 211-225			

Examiner Signature	<i>Jack Berman</i>	Date Considered	10/25/04
--------------------	--------------------	-----------------	----------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.